Freeform Search

US Pre-Grant Publication Full-Text Database

US Patents Full-Text Database US OCR Full-Text Database

Database: EPO Abstracts Database JPO Abstracts Database **Derwent World Patents Index IBM Technical Disclosure Bulletins**

Term:

((measur\$3 or determin\$3) near3 thickness) same (layer or film) same mask\$3 same pattern\$3 same (cmp or polish\$4) same (etch\$3 or remov\$3 or

Display:

Documents in <u>Display Format</u>: CIT Starting with Number 1

Generate: O Hit List O Hit Count O Side by Side O Image



Search History

DATE: Wednesday, January 26, 2005 Printable Copy Create Case

Set Name side by side	Query	<u>Hit</u> Count	Set Name result set
DB = 1	PGPB, USPT, USOC, EPAB, JPAB, DWPI, TDBD; PLUR=YES; OP=ADJ		
<u>L3</u>	((measur\$3 or determin\$3) near3 thickness) same (layer or film) same mask\$3 same pattern\$3 same (cmp or polish\$4) same (etch\$3 or remov\$3 or reduc\$3)	45	<u>L3</u>
<u>L2</u>	thickness same (layer or film) same mask\$3 same pattern\$3 same (cmp or polish\$4) same (etch\$3 or remov\$3 or reduc\$3)	1659	<u>L2</u>
<u>L1</u>	thickness same (layer or film) same mask\$3 same pattern\$3 same (cmp or polish\$4)	1885	<u>L1</u>

END OF SEARCH HISTORY